

Publikationen

(2006): Verfahren zur Kompensation von Streu-/Reflexionseffekten in der Teilchenstrahlolithographie.

(2006): Kelvin Probe Force Microscopy - An appropriate tool for the electrical characterisation of LED heterostructures. In: 17th European Symposium - Reliability of Electron Devices, Failure Physics and Analysis (ESREF) 2006, Wuppertal.

(2006): Kelvin Probe Force Microscopy - An appropriate tool for the electrical characterisation of LED heterostructures. In: Nanotech Northern Europe, Helsinki, Finland.

(2006): Kelvin Probe Force Microscopy - An appropriate tool for the electrical characterisation of LED heterostructures. In: Microelectronics Reliability, vol. 46, no. 9-11, pp. 1736-1740.

(2005): Method for compensating for scatter/reflection effects in particle beam lithography.